## Amendments to the Claims:

The listing of claims will replace all prior versions, and listings, of claims in the application:

## **Listing of Claims**:

1-23. (Cancelled)

- 24. (Currently Amended) A vacuum cleaning chamber of Claim [[23]]

  25, wherein said workpiece holding arrangement is constructed to hold at least
  one disk shaped or plate shaped workpiece, resides within said vacuum cleaning
  chamber and comprises at least one access slit slits are open to the interior of
  said vacuum cleaning chamber.
- 25. (Currently Amended) The chamber of Claim 24, wherein said holding arrangement defines for a holding plane for said disk-shaped or plate-shaped workpiece workpieces and said slit extends slits extend substantially parallel to said plane.
- 26. (Currently Amended) The chamber of Claim 25, wherein said slit extends slits extend laterally with respect to said holding plane.
  - 27.-28. (Canceled)

- 29. (Currently Amended) The chamber of Claim [[23]] <u>35</u>, wherein said plasma discharge section is a low-voltage discharge section.
- 30. (Previously Presented) The chamber of Claim 29, wherein said low-voltage discharge section comprises an electron-emitting hot cathode.
  - 31. (Canceled)
- 32. (Currently Amended) The chamber of Claim [[23]] <u>35</u>, wherein said tank arrangement feeds to said gas supply said gas comprising a working gas.
- 33. (Currently Amended) The chamber of Claim [[10]] <u>32</u>, wherein said working gas [[is]] <u>includes</u> at least one noble gas.
  - 34. (Canceled)
- 35. (New) A vacuum treatment chamber for generating disk-shaped workpieces with directly bondable surfaces, said chamber being a stand-alone chamber in ambient, comprising a plasma discharge section, a gas supply operatively connected with a gas tank arrangement predominantly containing nitrogen, a workpiece holding arrangement comprising a magazine with slits, each slit being arranged for a workpiece to be simultaneously treated in said vacuum treatment chamber.